

# **2006 Term Project Review**

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# **Project Goals & Design Constraints**

- Design a resonator to resonate at exactly 10 kHz ۲
  - Atmospheric pressure
  - Resonate at 10 kHz ± 0.5 kHz
  - Low actuation voltage
- **Design Constraints** ٠
  - Die size: 4mm X 4 mm
  - Lithography, etch constraints: 4 um (line and space)
  - Minimize the footing phenomenon \_
  - Resonance frequency: 10 kHz ± 0.5 kHz
  - Actuation voltage: The lower, the better



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#### **Measurement Considerations**

Why use biased AC voltage?



 $F \propto V_{\rm AC}^{2} = V_{\rm AC MAX}^{2} \cos^{2} \omega t$ 

 $\rightarrow$  DC term & 2 $\omega$  term remains





 $F \propto V^2$ 

 $F \propto (1 + \cos 2\omega t)$ 

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## 2006 Design Summary

	#		1	2	3	4	!	5	6	7	8	3	9	10	11
	Туре	#1	#2	#1	#1	#2	#1	#2	#1	#1	#1	#2	#1	#1	#1
	type	folded -flexure	folded -flexure	folded -flexure	folded	folded	folded -flexure	folded -flexure	folded	folded	folded	folded	folded -flexure	folded	guided -end
spring design	spring constant [N/m]	396	206.4	429.93	178	30.6	729	1978	2112	625	94.6	109.6	24.1	654	108.7
mass design	Mass [kg]	1.00E-07	4.70E-08	1.09E-07	5.19E-08	9.02E-09	1.29E-07	3.51E-07	4.01E-07	1.58E-07	2.20E-08	2.30E-08	6.13E-09	1.71E-07	2.75E-08
target frequency	[kHz]	10.02	10.55	10.00	9.32	9.27	11.96	11.95	11.60	10.00	10.40	11.00	9.98	9.85	10.00

result	actuation	ο	x	0	x	x	x	0	x	x	0	0	ο	ο	ο
	actuation frequency [kHz]	9.5	-	9.2	-	-	-	9.8	-	-	9.8	10	10.1	9.9	10
	applied voltage	24V (DC) 16V (AC)	-	12.5 (DC) 5V (AV)	-	-	-	9V (DC) 8.5V (AC)	-	-	24V (DC) 16V (AC)	40V (DC) 32V (AC)	- (DC) 10.1(AC)	28V (DC) 5V (AC)	4.8V (DC) 5V (AC)



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DC Voltage	24 V	DC Voltage	-
AC Voltage	16 V	AC Voltage	-
Natural Frequency	9.1 kHz ~ 10.1 kHz	Natural Frequency	-
Remarks	# of spring : 4	Remarks	# of spring : 8

[Design 1]

[Design 2]

• Too small etch hall → Release failure



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DC Voltage	12.5 V				
AC Voltage	5 V				
Natural Frequency	ISRC: 9.2 kHz KETI: 9.9 kHz				
Remarks	Spring width : 5um (ISRC Fab., KETI Fab.)				

• Less footing effect  $\rightarrow$  More accurate frequency

AC Voltage5 VNatural FrequencyISRC: 7.5 kHzRemarksSpring width : 10um<br/>(ISRC Fab.)

Footing effect → Frequency spec out



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DC Voltage	20 V	DC Voltage	15 V	
AC Voltage	15 V	AC Voltage	10 V	
Natural Frequency	8.3 kHz	Natural Frequency	9.27 kHz	
Remarks	Design 2/ISRC Fab.	Remarks	Design 2/KETI Fab.	

• Footing & Under cut difference  $\rightarrow$  Spring & Mass difference  $\rightarrow$  Frequency difference



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[Design 1]

[Design 2]

• All spring is close each other  $\rightarrow$  Wrong actuating mode



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L.	ayout]		Design]	
DC Voltage	-	DC Voltage	-	
AC Voltage -		AC Voltage	-	
Natural Frequency	-	Natural Frequency	-	
Remarks Designed Freq.: 9.475 kHz		Remarks Designed Free 10.01 kHz		
[Desi	gn 1]	[Des	ign 2]	

• Two beams are close etch other  $\rightarrow$  Electrostatic force problem

Large mass & short spring



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- Two modes are close etch other  $\rightarrow$  Wrong actuating mode
- Cleaning problem after release  $\rightarrow$  Particle under the structure



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Acc.V Mac 5.00 kV 71x	инически и и и и и и и и и и и и и и и и и и	Acc. V Magn WD 5.00 kV 58x 23.4	-1 500 μm

DC Voltage	24 V	DC Voltage	40 V
AC Voltage	16 V	AC Voltage	32 V
Natural Frequency	9.7 kHz ~ 10.3 kHz	Natural Frequency	10 kHz
Remarks	No Tuning	Remarks	Tuning Voltage : 0 V

[Design 1]

[Design 2]

• Using the negative stiffness effect

for natural frequency control



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Histogram

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Natural Frequency

## Conclusions & Q/A

- Layout Design with Fabrication error compensation •
  - Etch lag phenomenon, Footing effect, etc \_
- Release •
  - Anchor design issue
- Simple design ٠
- Negative Stiffness Effect
  - Can control frequency by applying voltage \_





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